

Lecture 6w: Process Modules IILecture 6: Process Modules II

- Announcements:
- HW#1 due today at 7:00 p.m.
- HW#2 online soon
- No office hours for me on Wednesday, 9/21, due to the BSAC Industrial Advisory Board Meeting
- No lecture next Thursday, 9/22, during the normal time period, again, due to IAB
 - ↳ Make-up lecture: TBD
- No lecture on Thursday, 9/29
 - ↳ Make-up lecture: TBD
- -----
- Today:
- Reading: Senturia, Chpt. 3; Jaeger, Chpt. 2, 3, 6
 - ↳ Example MEMS fabrication processes
 - ↳ Oxidation
 - ↳ Film Deposition
 - Evaporation
 - Sputter deposition
 - Chemical vapor deposition (CVD)
 - Plasma enhanced chemical vapor deposition (PECVD)
 - Epitaxy
 - Atomic layer deposition (ALD)
 - Electroplating
- Reading: Senturia, Chpt. 3; Jaeger, Chpt. 2, 4, 5
 - ↳ Lithography
 - ↳ Etching
 - Wet etching
 - Dry etching
- -----

- Last Time:
- Going through Module 3 ... continue with this
- ... then start going through Module 4